

09/937538
JC09 Rec'd PCT/PTO 25 SEP 2001

PATENT

81839.0102

Express Mail Label No. EL 894 944 374 US

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Michihiro MIZUNO

Serial No: Not assigned

Filed: September 25, 2001

For: METHOD FOR EVALUATING CONCENTRATION
OF METAL IMPURITIES IN SILICON WAFER

Art Unit: Not assigned

Examiner: Not assigned

**TRANSMITTAL OF INFORMATION DISCLOSURE
STATEMENT**

Box PCT
Assistant Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

The information disclosure statement submitted herewith is being filed concurrently with the subject application [37 C.F.R. § 1.97(b)] and contains items of information cited in the parent application No. PCT/JP01/00301.

If it should be determined that for any reason either an insufficient or excessive fee has been paid, please charge any insufficiency or credit any overpayment necessary to ensure consideration of the information disclosure statement for the above-identified application to Deposit Account No. 50-1314. A copy of this paper is enclosed.

Respectfully submitted,

HOGAN & HARTSON L.L.P.

Date: September 25, 2001

By:

Lawrence J. McClure
Lawrence J. McClure

Registration No. 44,228

Attorney for Applicant(s)

500 South Grand Avenue, Suite 1900
Los Angeles, California 90071
Telephone: 213-337-6700
Facsimile: 213-337-6701

Michihiro MIZUNO

Group Art Unit
Not assigned

FILING DATE IF
APPROPRIATEWLA - 72761/300 - #118560 v1